



**PATENT**

Case Docket No. MICRON.137DV2C1

Date: February 17, 2004

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant(s) : Ahn et al.  
Appl. No. : 10/719,501  
Filed : November 21, 2003  
For : INTEGRATED CIRCUIT  
INDUCTOR WITH A  
MAGNETIC CORE  
Examiner : Unknown  
Group Art Unit : Unknown

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

February 17, 2004

(Date)

Adeel S. Akhtar, Reg. No. 41,394

**TRANSMITTAL LETTER**

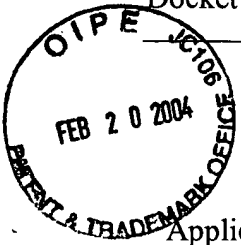
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Enclosed for filing in the above-identified application are:

- (X) An Information Disclosure Statement.
- (X) A PTO Form 1449 listing fifty-one (51) references.
- (X) The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment, to Account No. 11-1410.
- (X) Return prepaid postcard.

Adeel S. Akhtar  
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**INFORMATION DISCLOSURE STATEMENT**

Applicant : Ahn et al.  
App. No. : 10/719,501  
Filed : November 21, 2003  
For : INTEGRATED CIRCUIT INDUCTOR  
WITH A MAGNETIC CORE  
Examiner : Unknown  
Group Art Unit : Unknown

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Enclosed is form PTO-1449 listing 51 references that are of record in U.S. patent application No. 09/523,097, filed March 10, 2000, now issued as U.S. Patent No. 6,531,945 on March 11, 2003, which is the parent of U.S. divisional patent application No. 10/357,527, filed February 3, 2003 which is the parent of the present continuation application, and is relied upon for an earlier filing date under 35 U.S.C. § 120. Copies of the references are not submitted pursuant to 37 C.F.R. § 1.98(d).

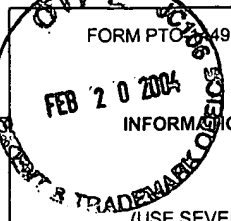
This Information Disclosure Statement is being filed with an RCE or within three months of the filing date of this application and no fee is required in accordance with 37 C.F.R. § 1.97(b)(1), (b)(2), or (b)(4).

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: February 17, 2004

By: Adeel S. Akhtar  
Adeel S. Akhtar  
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	FORM PTO 449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MICRON.137DV2C1	APPLICATION NO. 10/719,501
	APPLICANT Ahn, et al.			
	FILING DATE November 21, 2003		GROUP 2832	

U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
	1	3,881,244	05/06/75	Kendall			
	2	3,918,148	11/11/75	Magdo et al.			
	3	3,988,764	10/26/76	Cline, et al.			
	4	5,062,197	11/05/91	Charles			
	5	5,098,528	03/24/92	DeLalande, et al.			
	6	5,227,659	07/13/93	Hubbard			
	7	5,329,020	02/21/95	Chang			
	8	5,569,626	10/29/96	Kurtz et al.			
	9	5,781,091	7/14/98	Krone et al.			
	10	5,831,331	11/03/98	Lee			
	11	5,852,866	12/29/98	Kuettner			
	12	5,861,647	01/19/99	Zhao, et al.			
	13	5,863,024	01/26/99	Blind, et al.			
	14	5,896,078	04/20/99	Hayakawa et al.			
	15	5,898,020	04/27/99	Goyal et al			
	16	5,949,030	09/07/99	Fasano et al			
	17	6,166,422	12/26/00	Qian et al.			
	18	6,249,039	06/19/01	Harvey et al.			

FOREIGN PATENT DOCUMENTS								
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
	19	05198440	08/1993	JP				

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)	
	20	MacChesney, et al. "Chemical Vapor Deposition of Iron Oxide Films for Use as Semitransparent Masks." Journal of the Electrochemical Society. May, 1971. pp. 776-781.
	21	Shigematsu, et al. "Magnetic Properties of Amorphous Iron (III) Oxide Thin Films." Journal de Physique. March, 1979. pp. C2-153-154.
	22	Domke, et al. "Magnetic and Electronic Properties of Thin Iron Oxide Films." Surface Science. August, 1982. pp. 727-732.

EXAMINER	DATE CONSIDERED
*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED, INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.	

FORM PTO-1449	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. MICRON.137DV2C1	APPLICATION NO. 10/719,501
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (USE SEVERAL SHEETS IF NECESSARY)		APPLICANT Ahn, et al.	
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EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)	
	23	Ouchi, et al. "High Rate Deposition of Iron-Oxide Thin Film by Reactive Sputtering." IEEE Transactions on Magnetics. September, 1983. pp. 1980-1982.
	24	Kaito, et al. "Structure of Iron Oxide Films Prepared by Evaporating Various Iron Oxide Powders." Applications of Surface Science. October, 1984. pp. 621-630.
	25	Lin, et al. "Properties of RF Sputtered Iron Oxide Thin Films with CoCr and Nb as Dopants." IEEE Transactions on Magnetics. September, 1985. pp. 1462-1464.
	26	Joshi, et al. "Pulsed Laser Deposition of Iron Oxide and Ferrite Films." Journal of Applied Physics. November, 1988. pp. 5647-5649.
	27	Li, et al. "Preparation of Amorphous Iron-containing and Crystalline Iron Oxide Films by Glow Discharge and Their Properties." Materials Science and Engineering. 1990. pp. 5-13.
	28	Dubin, Valery M. "Formation Mechanism of Porous Silicon Layers Obtained by Anodization of Monocrystalline N-type Silicon in HF Solutions." Surface Science. February, 1992. pp. 82-92.
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	32	Gokturk, et al. "Electric and Magnetic Properties of a Thermoplastic Elastomer Incorporated with Ferromagnetic Powders." IEEE Transactions on Magnetics. November, 1993. pp. 4170-4176.
	33	Nedkov, et al. "Microwave Polymer-Ferroxide Film Absorbers." IEEE Transactions on Magnetics. November, 1994. pp. 4545-4547.
	34	Itoh, et al. "Ferrite Plating of Ba-Containing Iron Oxide Films Using Chelated Highly Alkaline (pH=11-13) Aqueous Solutions." Japanese Journal of Applied Physics. March, 1995. pp. 1534-1536.
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	40	Vadera, et al. "Preparation and Study of Finely Dispersed Magnetic Oxide in Polymer Matrix." Journal de Physique IV. March, 1997. pp. C1-549-C1-550.
	41	Kim, et al. "Surface Micromachined Solenoid Inductors for High Frequency Applications." 1997 International Symposium on Microelectronics Proceedings. pp. 1-8.
	42	Ouyang, et al. "Structure and Magnetic Properties of Iron Oxide Films Deposited by Excimer Laser Ablation of a Metal-Containing Polymer." Materials Research Bulletin. 1997. pp. 1099-1107.
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	44	Liu, et al. "Layer-by-Layer electrostatic Self-assembly of Nanoscale Fe <sub>3</sub> O <sub>4</sub> Particles and Polyimide Precursor on Silicon and Silica Surfaces." Applied Physics Letter. October, 1997. pp. 2265-2267.
	45	Nam, et al. "High-Performance Planar Inductor on Thick Oxidized Porous Silicon (OPS) Substrate." IEEE Microwave and Guided Wave Letters. August, 1997. pp. 236-238.
	46	Park, et al. "Ferrite-based Integrated Planar Inductors and Transformers Fabricated at Low Temperature." IEEE Transactions on Magnetics. September, 1997. pp. 3322-3324.
	47	Soh, et al. "Ultra-low Resistance, Through-Wafer VIA (TWV) Technology and Its Applications in Three Dimensional Structures on Silicon." 1998 International Conference on Solid State Devices and Materials Proceedings. pp. 284-285.
	48	Park, et al. "Fully Integrated Micromachined Inductors with Electroplated Anisotropic Magnet Cores." 1998 Applied Power Electronics Conference and Exposition Proceedings. pp. 379-385.

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	49	Namkung, et al. "Effects of Heat Treatment on the Magnetic Properties of Polymer-bound Iron Particle Cores." Journal of Applied Physics. June, 1998. pp. 6474-6476.
	50	Dimitrov, et al. "Stoichiometry and Magnetic Properties of Iron Oxide Films." 1997 Fall MRS Symposium Proceedings. pp. 89-94.
	51	Ahn, A Fully Integrated Planar Toroidal Inductor with a Micromachined Nickel-Iron Magnetic Bar, 09/1994, IEEE Transactions on Components, Packaging, and Manufacturing Technology, Part A, Vol. 17 pages 463-469.

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